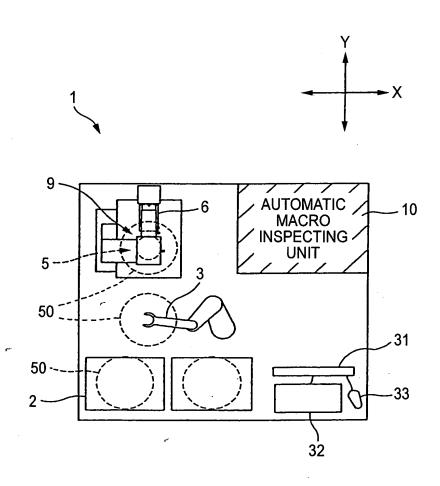
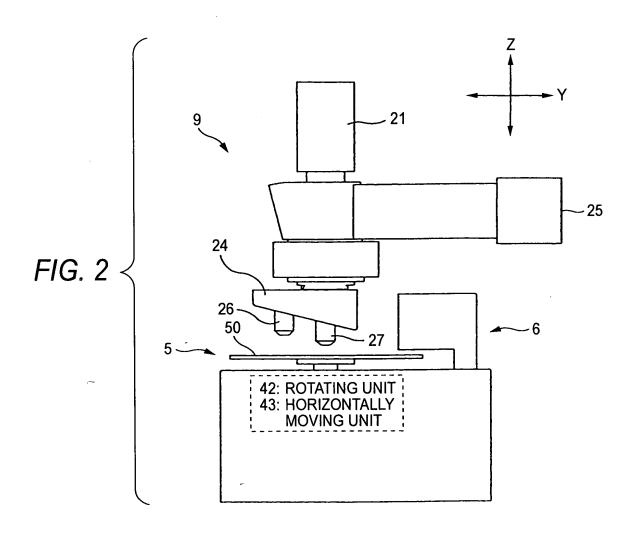


Q78681 10/721,381 Filed: November 25, 2003 Darryl Mexic (202) 293-7060 Takayasu YAMAMOTO, et al. INSPECTING DEVICE FOR SEMICONDUCTOR WAFER Page 1 of 8

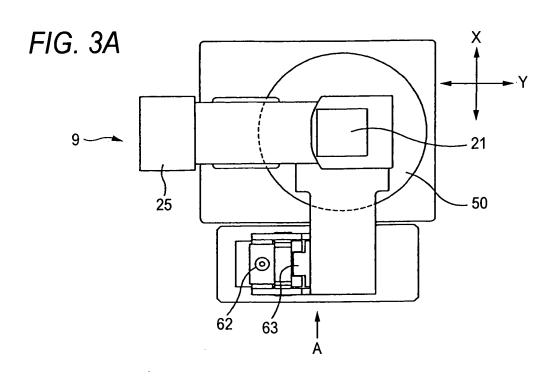
FIG. 1

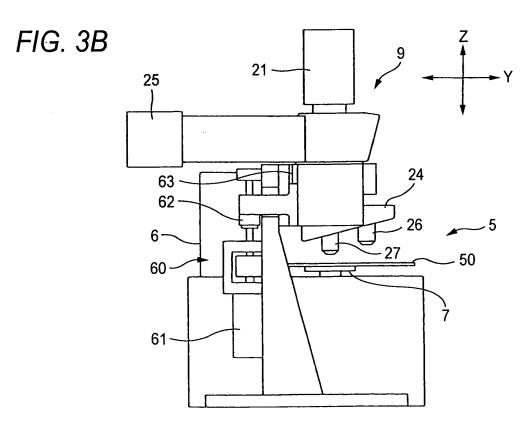


Q78681 10/721,381 Filed: November 25, 2003 Darryl Mexic (202) 293-7060 Takayasu YAMAMOTO, et al. INSPECTING DEVICE FOR SEMICONDUCTOR WAFER Page 2 of 8



Q78681 10/721,381 Filed: November 25, 2003 Darryl Mexic (202) 293-7060 Takayasu YAMAMOTO, et al. INSPECTING DEVICE FOR SEMICONDUCTOR WAFER Page 3 of 8





Q78681 10/721,381 Filed: November 25, 2003 Darryl Mexic (202) 293-7060 Takayasu YAMAMOTO, et al. INSPECTING DEVICE FOR SEMICONDUCTOR WAFER Page 4 of 8

FIG. 4A

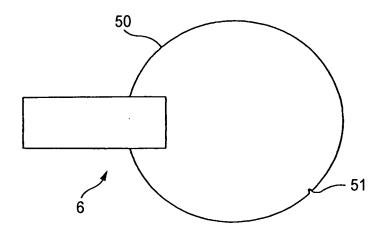
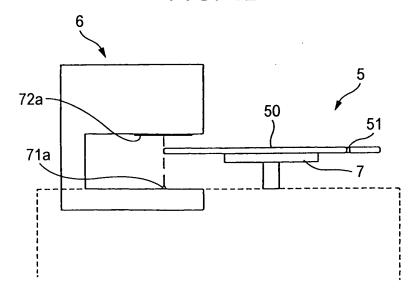
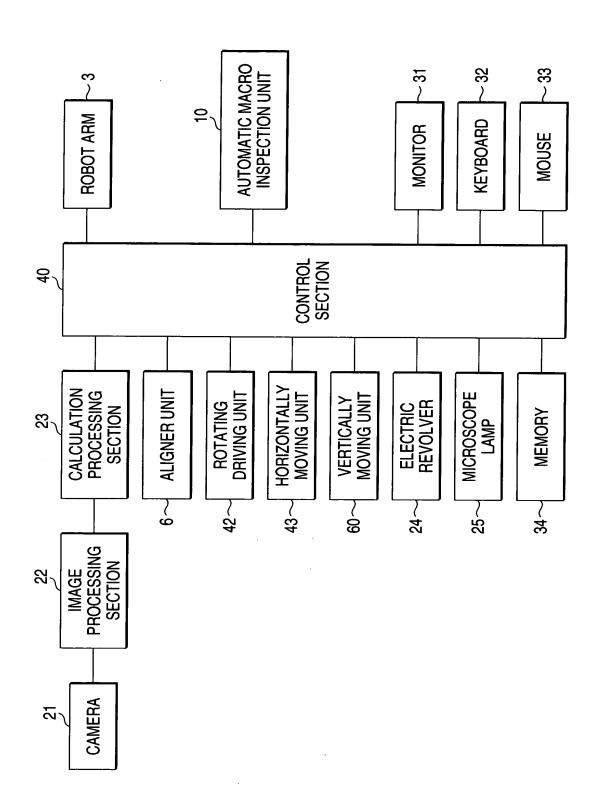
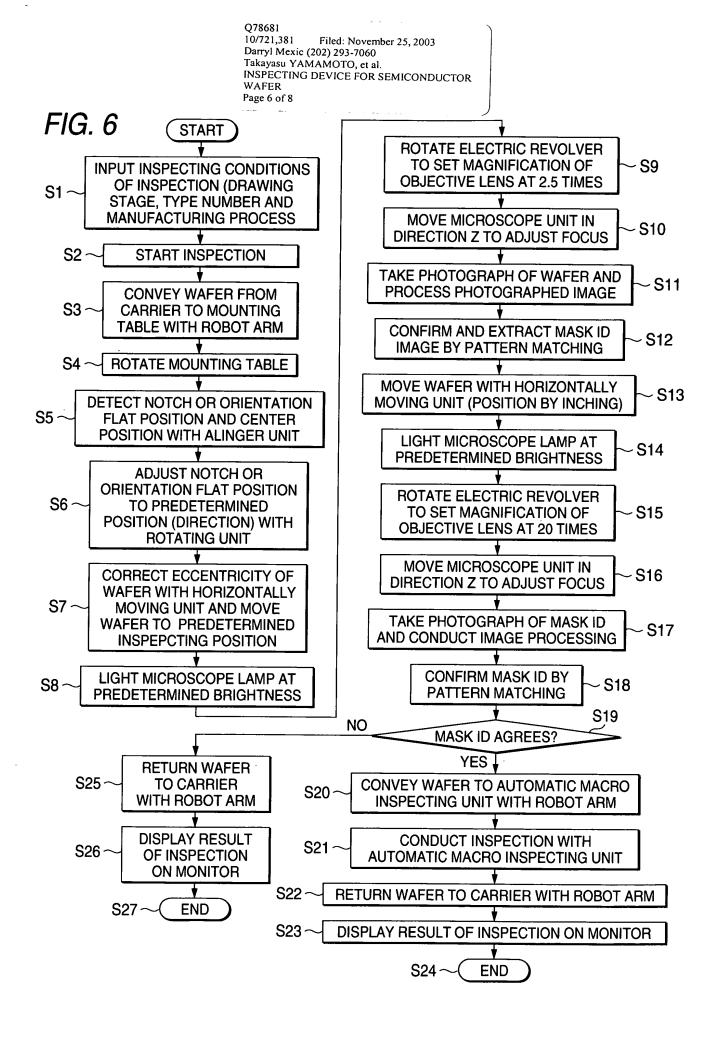


FIG. 4B









Q78681 10/721,381 Filed: November 25, 2003 Darryl Mexic (202) 293-7060 Takayasu YAMAMOTO, et al. INSPECTING DEVICE FOR SEMICONDUCTOR WAFER Page 7 of 8

FIG. 7

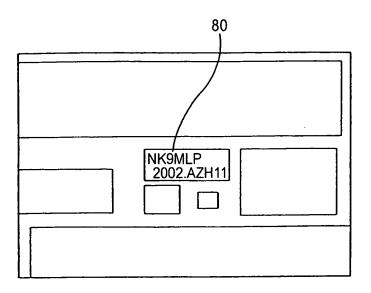
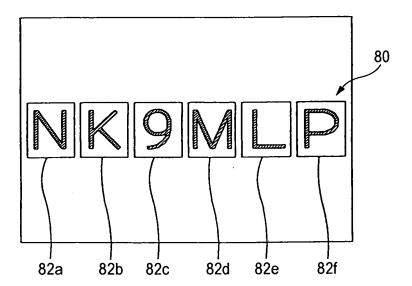


FIG. 8



Q78681 10/721,381 Filed: November 25, 2003 Darryl Mexic (202) 293-7060 Takayasu YAMAMOTO, et al. INSPECTING DEVICE FOR SEMICONDUCTOR WAFER Page 8 of 8

FIG. 9A

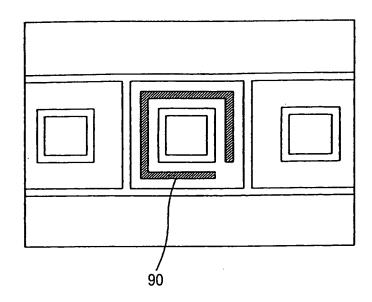


FIG. 9B

